## INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

Docket number (Optional)	Application Number		
15689.49.7	10/674,003		
Applicant(s)			
Takehi	ro Nakamura et al.		
Takehi Filing Date	ro Nakamura et al.  Group Art Unit		

			U.S. PATE	NT DOCUMENTS				
*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS		G DATE OPRIRATE
		U.	S. PATENT APPL	ICATION PUBLICATIONS	S			
*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS		G DATE OPRIRATE
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			FOREIGN PA	TENT DOCUMENTS				
						Translation		slation
-	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	YES	NO
/O.A./	1	0 682 418 A2 CN1126930	05/12/1995	EPO	H0487	005	X	
/O.A./	2	CN1120930	7/17/1996	China	H04B7	005	X	
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EXAMINER: I not considered.	nitial if cit: Include co	ation considered, whether or not o	itation is in confor	mance with MPEP Section (	509; Draw line th	rough citation if	not in confo	rmance and

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*Examiner Initial	OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
/O.A./	3	Chinese Office Action for Chinese Patent Application No.: 20031010330.1
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EXAMINER	/Olu	mide Ajibade Akonai/ DATE CONSIDERED 05/18/2009
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